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AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 1765
PATENT APPLICATION
Attorney Docket No. Q55902

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Makoto KASHIWAYA, et al.

Appln. No.: 09/534,207

Group Art Unit: 1765

Confirmation No.: 2981

Examiner: Duy Vu Deo

Filed: March 24, 2000

For: CARBON LAYER FORMING METHOD

#11 BAE
12/6/02
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DEC 05 2002
TC 1700

AMENDMENT UNDER 37 C.F.R. § 1.116

ATTN: BOX AF
Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated May 14, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please add the following new claims:

Claim 7. (New) The method of forming a carbon layer by vapor phase deposition according to claim 5, wherein the carbon layer, the intermediate layer, and the lower protective layer are successively formed on the thermal head under a continuous vacuum.

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